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THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoru Okamoto                      Art Unit : 1765  
Serial No. : 10/689,617                      Examiner : Lan Vinh  
Filed : October 22, 2003  
Title : METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD  
FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING  
SEMICONDUCTOR DEVICE

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

SUPPLEMENTAL AMENDMENT

Prior to examination, please amend the application as indicated on the following pages.